

Notice of References Cited

Application/Control No.

10/026,125

Applicant(s)/Patent Under
Reexamination
CHOU ET AL.

Examiner

Evan Pert

Art Unit

2829

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-5,581,510	12-1996	Furusho et al.	365/201
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
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	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
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*A copy of this reference is not being furnished with this Office action (See MPEP § 707 05(a))
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